

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): Takenori HIROSE et al.

Serial No.: Not yet assigned – Continuation of Serial No. 09/622,570

Filed: Even date herewith

For: **A THIN FILM THICKNESS MEASURING METHOD AND APPARATUS,  
AND METHOD AND APPARATUS FOR MANUFACTURING A THIN  
FILM DEVICE USING THE SAME**

Group: 2873 (expected)

Examiner: Jack Dinh (expected)

**CLAIM FOR PRIORITY**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

November 13, 2003

Sir:

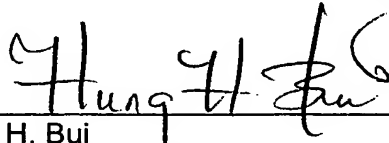
Pursuant to 35 U.S.C. §119 and 37 CFR 1.55, the Applicants hereby claim the right of priority based on the following foreign applications filed in Japan:

Application No. 10-110384 filed on April 21, 1998; and

Application No. 10-299311 filed on October 21, 1998.

A certified copy of these foreign application was filed on August 18, 2000, in application Serial No. 09/622,570, the parent application of the present continuation application.

Respectfully submitted,  
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